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## **PATENT APPLICATION**

IN THE UNITED STATES PATE	ENT AND TRADEMARK OFFICE
MASATAKA ITO Application No.: 10/091,461	) Examiner: S. Isaac ) Group Art Unit: 2812 )
Filed: March 7, 2002  For: SOI SUBSTRATE, ANNEALING METHOD THEREFOR, SEMICONDUCTOR DEVICE HAVING THE SOI SUBSTRATE, AND METHOD OF MANUFACTURING THE SAME	) : ) : ) : ) : Date: June 21, 2005
Mail Stop Amendment Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450	·

## **INFORMATION DISCLOSURE STATEMENT**

Sir:

In compliance with the duty of disclosure under 37 C.F.R. § 1.56 and in accordance with the practice under 37 C.F.R. §§ 1.97 and 1.98, the Examiner's attention is directed to the documents listed on the enclosed Form PTO-1449. Copies of the listed documents are also enclosed.

The listed documents were cited in a Search Report which issued in an European patent application corresponding to the subject application. A copy of the European Search Report, which is dated May 24, 2005, is enclosed.

The Sasaki article includes an English-language abstract.

STATEMENT UNDER 37 C.F.R. § 1.97(e)

Each item of information in this Information Disclosure Statement was first

cited in any communication from a foreign Patent Office in a counterpart foreign

application not more than three months prior to the filing date of this Statement.

**FORMAL MATTERS** 

No fee is believed due; however, any fee required in connection with this

paper should be charged to Deposit Account No. 06-1205.

**CONCLUSION** 

It is respectfully requested that the above information be considered by the

Examiner and that a copy of the enclosed Form PTO-1449 be returned indicating that such

information has been considered.

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Applicant's undersigned attorney may be reached in our Costa Mesa,

California office by telephone at (714) 540-8700. All correspondence should continue to

be directed to our address given below.

Respectfully submitted,

Damond E. Vadnais

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New York, New York 10112-3800

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FORM PTO 1449 (modified)  U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY DOCKET NO. 00862.022541.	APPLICATIO 10/091,4	ON NO. 461	IPE OCIO		
LIST OF REFERENCES CITED BY APPLICANT(S) (Use several sheets if necessary)			MASATAKA ITO			N 2 2 2005 E	
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			U.S. PATENT DOCUMENTS			TARB	
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	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES/NO/ OR ABSTRACT	
	0 926 707	06/30/1999	EP	-			
	0 926 718	06/30/1999	EP				
	0 817 248	01/07/1998	EP				
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	H. Aga, et al Wafers", Jp	., "Study of HF De n. J. Appl. Phys., \	efects in Thin, Bonded Silicon-on-Ins Vol. 38, May 1999, pp. 2694-2698.	sulator D	ependent	on Original	
G. Sasaki, et al., "Microstructure Around Indentation of Chemical Vapor Deposition (CVD)-SiC Observed by Transmission Electron Microscopy", Yogyo-Kyokai-Shi Japan, Vol. 94, No. 8, 1986, pp. 779-783.							
EXAMINER			DATE CONSIDERED				

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<sup>\*</sup>EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.